

PRINTER RUSH

(PTO ASSISTANCE)

IPW

Application : 09/076431

Examiner : Mathew

GAU : 2851

From : Tai

Location : IDC FMF FDO

Date : 10-15-05

Tracking # : 6126125

Week Date : 7-12-05

DOC CODE	DOC DATE	MISCELLANEOUS
<input type="checkbox"/> 1449		<input type="checkbox"/> Continuing Data
<input type="checkbox"/> IDS		<input type="checkbox"/> Foreign Priority
<input type="checkbox"/> CLM		<input type="checkbox"/> Document Legibility
<input type="checkbox"/> IIFW		<input type="checkbox"/> Fees
<input type="checkbox"/> SRFW		<input type="checkbox"/> Other
<input type="checkbox"/> DRW		
<input type="checkbox"/> OATH		
<input type="checkbox"/> 312		
<input checked="" type="checkbox"/> SPEC	<u>6-6-01</u>	

[RUSH] MESSAGE:

On Page 9 of the specification submitted on 6-6-01 there is a reference on Line 2 to a Figure 9A. Figure 9A does not exist on the drawing sheets of this Application.

Please verify

Thank You

Tai

[XRUSH] RESPONSE: Changed "9a" to "8", as FIG. 8 is the only figure on which reference numeral 1304 appears.

INITIALS: dsf

NOTE: This form will be included as part of the official USPTO record, with the Response document coded as XRUSH.

REV 10/04

12/19/05
Fig. 9 is a process flow diagram which illustrates the steps associated with processing a wafer, i.e., step 1304 of Fig. 9a, in accordance with an embodiment of the present invention.

Fig. 10a is a diagrammatic representation of a fine stage which is substantially coupled to a coarse stage through opposing motors in accordance with an embodiment of the present invention.

Fig. 10b is a diagrammatic representation of a fine stage which may be moved by a coarse stage through contact with bumpers on the coarse stage in accordance with an embodiment of the present invention.

DETAILED DESCRIPTION OF THE EMBODIMENTS

Increasing the throughput requirements of a reticle scanning stage often requires that acceleration capabilities of the reticle scanning stage be increased, and causes the accuracy associated with the reticle scanning stage to be compromised. This compromise is due at least in part to the fact that actuators which are capable of higher accelerations are generally more difficult to control and, hence, less accurate. In addition to being less accurate, large actuators are also difficult to position such that a line of force associated with the actuators may cross through the center of gravity on the reticle scanning stage. When the line of force is not through the center of the center of gravity on the reticle scanning stage, then a fairly significant balancing mass which increases the overall size of the reticle scanning stage may be needed to balance the reticle scanning stage. In order to increase the accuracy associated with a reticle scanning stage and to substantially minimize the size of the reticle scanning stage, smaller, more controllable actuators may be used with the reticle scanning stage, typically at the expense of acceleration capabilities.

As will be appreciated by those skilled in the art, during a scan, high accuracy is generally only important in a zero acceleration portion of a scan trajectory. That is, when